

ABSTRACT

Conduit System for a Lithographic Apparatus, Lithographic Apparatus, Pump, and Method for Substantially Reducing Vibrations in a Conduit System

A conduit system for a lithographic apparatus includes at least one conduit for guiding a liquid or liquid-gas mixture, and a gas injection nozzle configured to introduce a gas in the liquid or liquid-gas mixture to at least partially absorb pressure peaks or waves in said liquid or liquid-gas mixture. In an embodiment the gas injection nozzle may be arranged in a pump of the conduit system. The pump further includes a pump inlet, a pump outlet and a pump chamber between the pump inlet and the pump outlet for compression of the liquid or liquid-gas mixture.

Figure 8